

ABSTRACT

An inspection device 1 includes a reference signal output section 24, a removal processing section 25, a gain setting section 26, and an electrical characteristic measurement section 28. The reference signal output section 24 is connected to an external power supply device 2 in electrical parallel with a semiconductor sample S, and outputs a reference signal according to the output of the external power supply device 2. The removal processing section 25 performs processing for removing a noise component, which is due to the output of the external power supply device 2 from the current signal output from the semiconductor sample S, based on the reference signal and outputs a processing signal. The gain setting section 26 sets the value of the gain of the reference signal output section based on the processing signal. The electrical characteristic measurement section 28 measures the electrical characteristics of the semiconductor sample S based on the processing signal subjected to the removal processing performed based on the reference signal from the reference signal output section for which the value of the gain has been set by the gain setting section.

Figure 1